

ABSTRACT OF THE DISCLOSURE

A stamper forming method includes following steps of forming a photoresist layer on a substrate, forming a patterned semi-blocked layer on the photoresist layer, exposing the photoresist layer with a light beam, developing the photoresist layer, and sputtering towards the photoresist layer to form a metal layer. In this case, the semi-blocked layer decays the intensity of the light beam, and partially blocks the light beam.